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**INFORMATION DISCLOSURE
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PTO/SB/08A(10-01)
Approved for use through 10/31/2002. OMB 051-0031
US Patent & Trademark Office: U.S. DEPARTMENT OF COMMERCE

Complete if Known

Application Number	10/765,619
Filing Date	January 27, 2004
First Named Inventor	Ahn, Kie
Group Art Unit	2891
Examiner Name	Sarkar, Asok

Sheet 1 of 3

Attorney Docket No: 1303.033US2

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Asok Kumar Sarkar

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First Named Inventor	Ahn, Kie
Group Art Unit	2891
Examiner Name	Sarkar, Asok

Sheet 2 of 3

Attorney Docket No: 1303.033US2

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Examiner Initials*	Cite No ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
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OTHER DOCUMENTS -- NON PATENT LITERATURE DOCUMENTS			
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